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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Yuji ONO et al.**

Serial No.: **09/940,788**

Group Art Unit: **1746**

Filed: **August 29, 2001**

Examiner: **Joseph L. Perrin**

P.T.O. Confirmation No.: **4613**

For. **SINGLE WAFER TYPE SUBSTRATE CLEANING METHOD AND APPARATUS**

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

July 9, 2003

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated March 11, 2003 for one month from June 11, 2003 to July 11, 2003.

Attached please find a check in the amount of \$110.00 to cover the cost of the extension for a large entity. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

ARMSTRONG, WESTERMAN & HATTORI, LLP

  
Daniel A. Geselowitz, Ph.D.

Agent for Applicants

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Atty. Docket No. **011075**  
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